Glass Thickness Compensation Near Infrared Objective Lenses PAL-NIR-LC RoHS W3465

This is a high NA infinity corrected objective lens for laser processing (femtosecond laser and fundamental of YAG laser). Its glass-thickness- compensation optical design makes it possible to realize an ideal beam spot size and quality even if it was processed thorough a cover glass.

• Two kinds objective lenses are available. They are designed to correct aberration depending on the thickness of cover glass.

• With its long working infinity correction function; this objective lens can be used for a laser system and coaxial observation.

Application Systems

Optics & Optical Coatings

Opto-Mechanics

Bases

Manual Stages

Actuators & Adjusters

Motoeized Stages

Light Sources & Laser Safety

Microscope Unit

Interferometers

Inspection/ Observation

Bio-photonics

Laser Processin

Alignment

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• Laser Damage Threshold(reference): 0.1J/cm² (532nm), 0.2 J/cm² (1064nm) (Laser pulse width: 10ns, repetition frequency: 20Hz) X09 UBIA AIN

• It is also used for the observation of Near Infrared light. • High resolution type (NA=0.65) is also available.

• This objective lens can be used with a pulse laser of visible light (532nm).

Guide

- Available fixed objective lens holder (LHO-26). WEB Reference Catalog Code W4024
- When the objective lens is fixed to a 2 axis holder, please consult our Sales Division.

(t= 0.7 mm and 1.1 mm)

For laser processing, we offer a dichoric block (DIMC) and for laser unit with coaxial illumination and observation (OUCI-2) WEB Reference Catalog Code W2041, WEB Reference Catalog Code W2012

Attention

C.G.=1.1

φ34

- When an objective lens is used in laser processing, use the diameter of the incident beam to extend to a size of half the pupil diameter (1/e²). A small light spot cannot be achieved when the incident beam is too narrow. Please note if there is a laser energy density increase, there will be a high possibility of damage to the objective lens.
- When the thickness of cover glass is not same as the specified, designed specifications may not be achieved due to aberration.
- If the incident laser beam femtosecond is below 100fs, there is a possibility that the pulse width will spread. Magnification is the value when using the imaging lens f=200mm. When used in a microscope lens barrel from other manufacturers there may be different magnifications. The actual magnification should be calculated from the ratio of the focal length of the objective lens and the focal length of the imaging lens to verify the focal length of the imaging lens barrel to be used.

Outline Drawing

PAL-20-NIR-LC07



PAL-20-NIR-LC11 (M26 P=0.706) 20.2 (Working Distance) W26 (ISO 8038

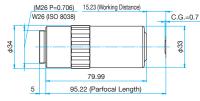
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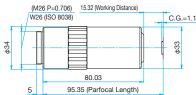
95 (Parfocal Length)

ф34

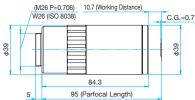
PAL-50-NIR-L-LC07

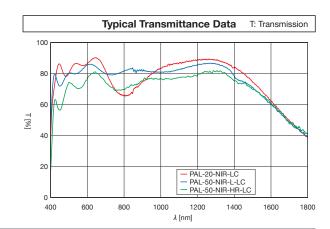


PAL-50-NIR-L-LC11



PAL-50-NIR-HR-LC07





Specifications

Part Number	Item name	Magnification		Numerical aperture NA			Focal depth (λ=550nm) [μm]		eld of view (Imaging device 1/2-inch) [mm]	Weight [kg]
PAL-20-NIR-LC07	LCD PlanApo NIR 10x (t0.7)	20×	10	0.40	19.98	0.69	±1.7	φ1.7	0.24×0.32	0.36
PAL-20-NIR-LC11	LCD PlanApo NIR 20x (t0.7)	20×	10	0.40	19.85	0.69	±1.7	φ1.7	0.24×0.32	0.36
PAL-50-NIR-L-LC07	LCD PlanApo NIR HR 20x (t0.7)	50×	4	0.45	15.01	0.61	±1.4	φ0.46	0.10×0.13	0.34
PAL-50-NIR-L-LC11	LCD PlanApo NIR 50x (t0.7)	50×	4	0.45	14.97	0.61	±1.4	φ0.46	0.10×0.13	0.34
PAL-50-NIR-HR-LC07	LCD PlanApo NIR HR 50x (t0.7)	50×	4	0.67	10.48	0.41	±0.6	φ0.46	0.10×0.13	0.48

